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				databases easy search	
		Adva	nced S	earch: INSPEC - 1969 to c	late (INZZ)
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Search history:

No.	Database	Search term	Info added since	Results	
1	INZZ	reset ADJ voitage\$1 SAME offset ADJ voitage\$1 SAME damp\$3 ADJ pulse\$1	unrestricted	0	-
2	INZZ	method WITH micromirror\$1 AND voltage\$1 WITH (offset OR reset)	unrestricted	0	-

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Classification codes D: Information Technology Classification codes E: Manufacturing & Production

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Classification codes A: Physics, 0-1		
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Classification codes A: Physics, 4-5		
Classification codes A: Physics, 6		
Classification codes A: Physics, 7		
Classification codes A: Physics, 8		
Classification codes A: Physics, 9		
Classification codes B: Electrical & Electronics	s, 0-5	
Classification codes B: Electrical & Electronics	s, 6-9	
Classification codes C: Computer & Control		

Search Query Case No. 10/749,469

3 (reset adj voltage\$1) same (offset adj voltage\$1) same (damp\$3 adj pulse\$1) .	US-PGPUB; USPA USOCR; EPO; JPC DERWENT; IBM_TDB
4648 (359/290,291,296,298,214,224,230,212,223).CCLS.	US-PGPUB; USPA USOCR; EPO; JPO DERWENT; IBM_TDB
5 (method with micromirror\$1 with control\$4).ti.	US-PGPUB; USPA USOCR; EPO; JPO DERWENT; IBM_TDB
90 (method with micromirror\$1).ti.	US-PGPUB; USPA USOCR; EPO; JPO DERWENT; IBM_TDB
27 S5 and voltage\$1	US-PGPUB; USPA USOCR; EPO; JPO DERWENT; IBM_TDB
82 (method with micromirror\$1) and (voltage\$1 with (offset or reset))	US-PGPUB; USPA USOCR; EPO; JPO DERWENT; IBM_TDB
45 S3 and S7	US-PGPUB; USPA USOCR; EPO; JPO DERWENT; IBM_TDB
4700 (359/290,291,296,298,214,224,230,212,223,295).CCLS.	US-PGPUB; USPA USOCR; EPO; JPO DERWENT; IBM_TDB
45 S9 and S7	US-PGPUB; USPA USOCR; EPO; JPO DERWENT; IBM_TDB
12 (("4662746") or ("4956610") or ("5061049") or ("5083857") or ("5583688" or ("5706123") or ("5764208") or ("5768007") or ("5771116") or ("5912758") or ("6008785") or ("6583921")).PN.) USPAT; USOCR

Search Results Case No. 10/749,469

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USPAT	Spatial light modulator and method	359/223
USPAT	Current density measurement system by self-sustaining	324/425
	magnetic oscillation	
USPAT	Spatial light modulator and method	359/224
USPAT	Multi-level deformable mirror device	359/291
USPAT	Multi-level digital micromirror device	359/291
USPAT	Switched control signals for digital micro-mirror device	359/291
	with split reset	
USPAT	Reset scheme for spatial light modulators	345/85
USPAT	Phase matched reset for digital micro-mirror device	359/290
USPAT	Multiple bias level reset waveform for enhanced DMD	359/295
	control	
USPAT	Bipolar reset for spatial light modulators	359/290
USPAT	Generating load/reset sequences for spatial light	345/85
	modulator	
USPAT	Micromechanical device and method for non-contacting	359/291
	edge-coupled operation	
USPAT	Micromirror driver and method of controlling micromirror	359/290
	driver	
US-PGPUB	Damped control of a micromechanical device	359/291
US-PGPUB	Damped control of a micromechanical device	359/291
US-PGPUB	Damped control of a micromechanical device	359/223
	USPAT	USPAT Current density measurement system by self-sustaining magnetic oscillation USPAT Spatial light modulator and method USPAT Multi-level deformable mirror device USPAT Multi-level digital micromirror device USPAT Switched control signals for digital micro-mirror device with split reset USPAT Reset scheme for spatial light modulators USPAT Phase matched reset for digital micro-mirror device USPAT Multiple bias level reset waveform for enhanced DMD control USPAT Bipolar reset for spatial light modulators USPAT Generating load/reset sequences for spatial light modulator USPAT Micromechanical device and method for non-contacting edge-coupled operation USPAT Micromirror driver and method of controlling micromirror driver USPAT Micromirror driver and method of controlling micromirror driver USPAT Damped control of a micromechanical device US-PGPUB Damped control of a micromechanical device